

MAINTAINING A REACTOR CHAMBER OF A CHEMICAL
VAPOR DEPOSITION SYSTEM

Inventors: Jin (nmi) Zhao, et al. Atty Docket No. TI-35855 (032350.B505)
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FIG. 1 1/2

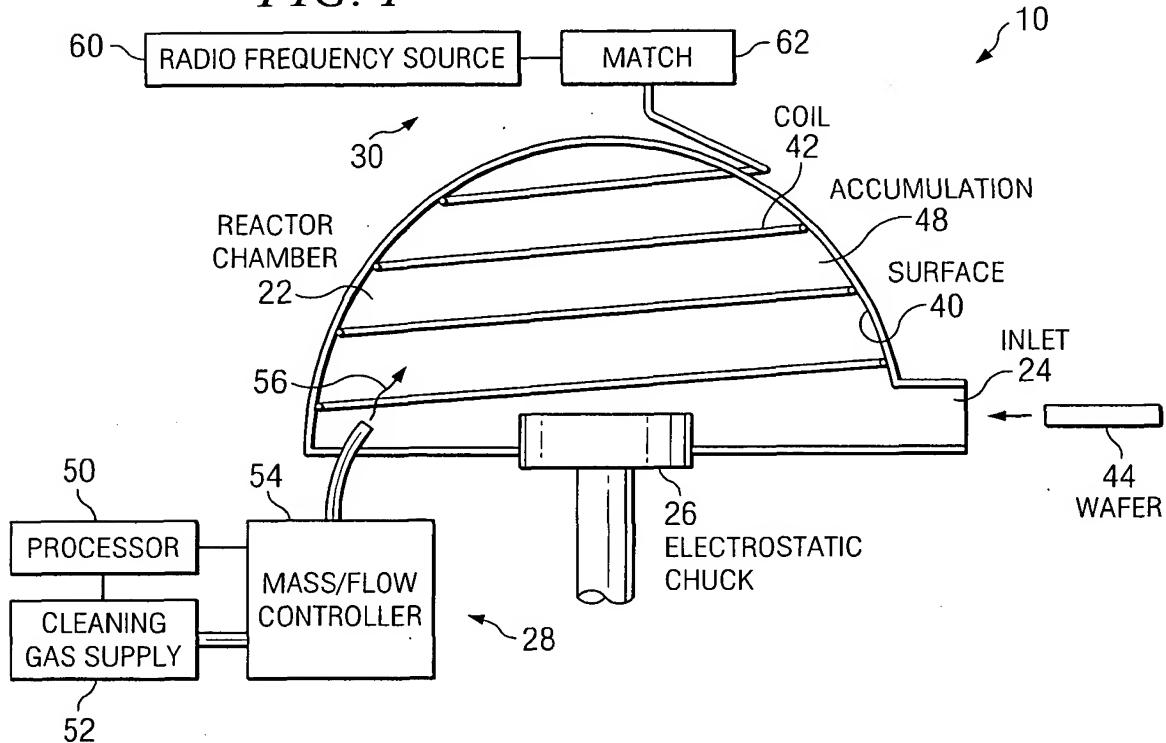
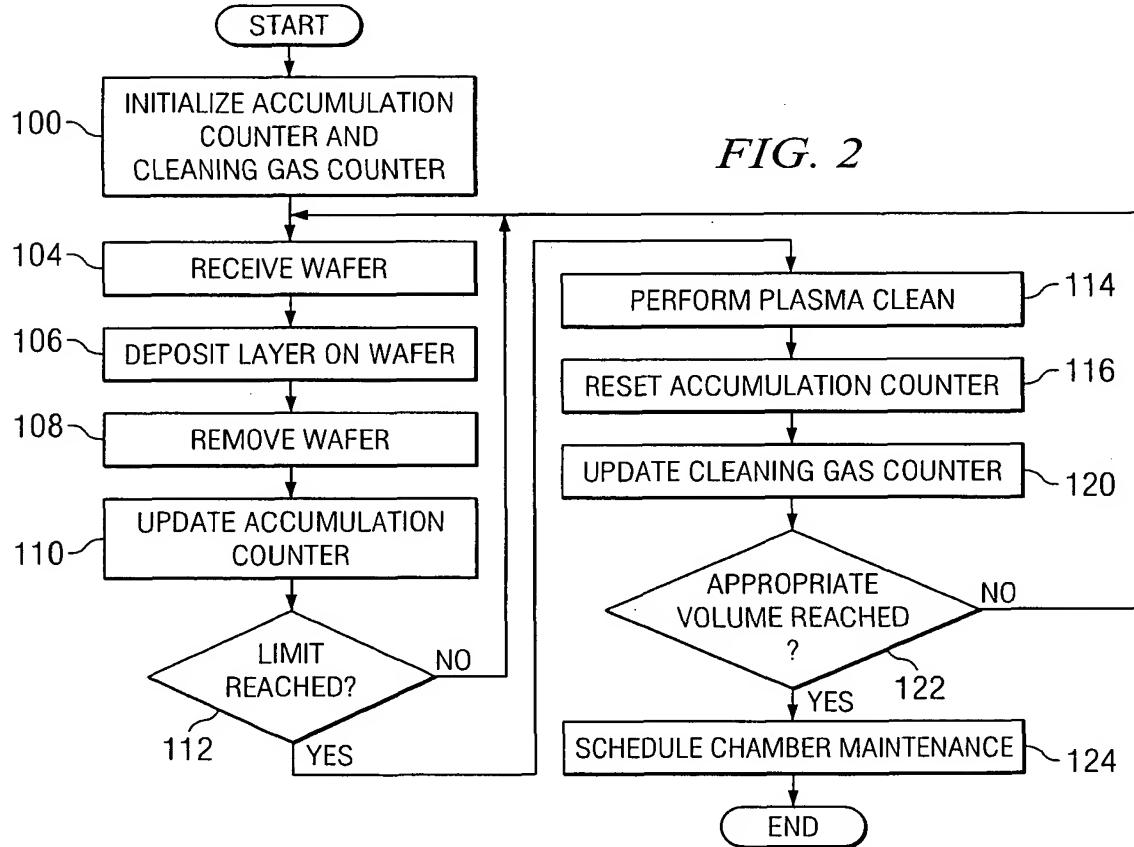


FIG. 2



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FIG. 3

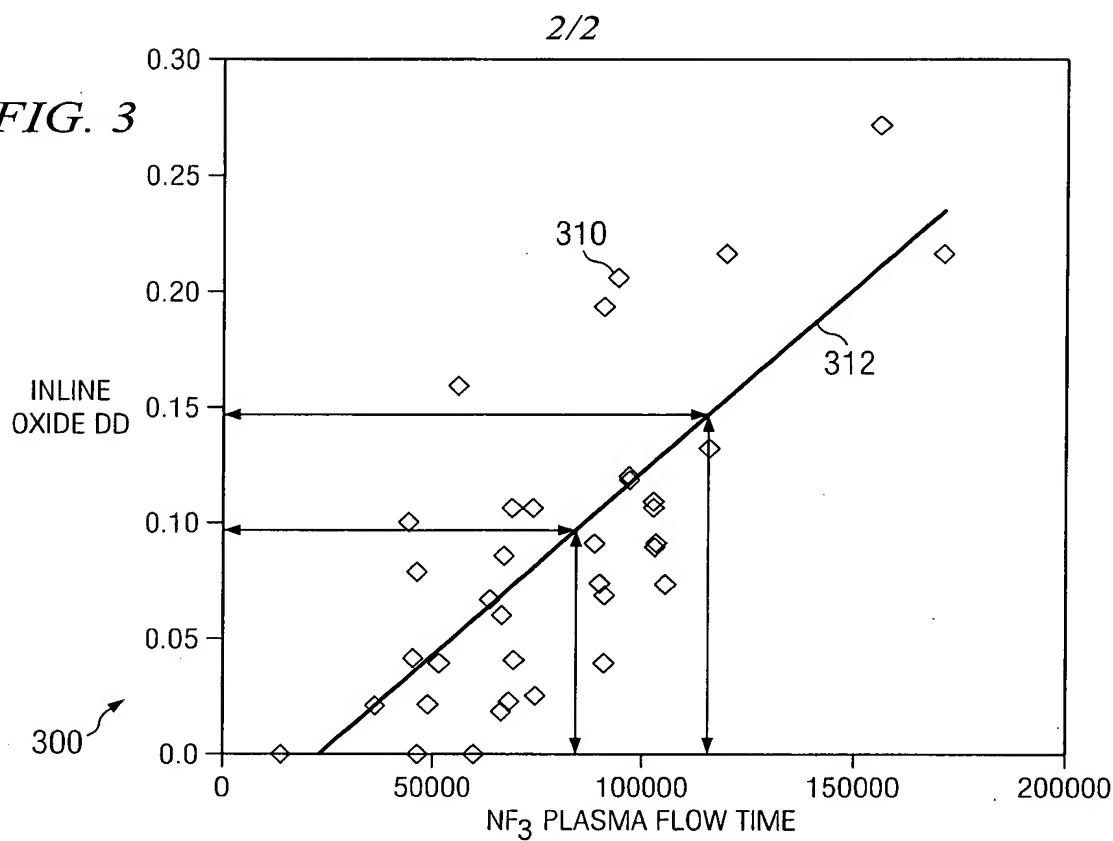


FIG. 4

